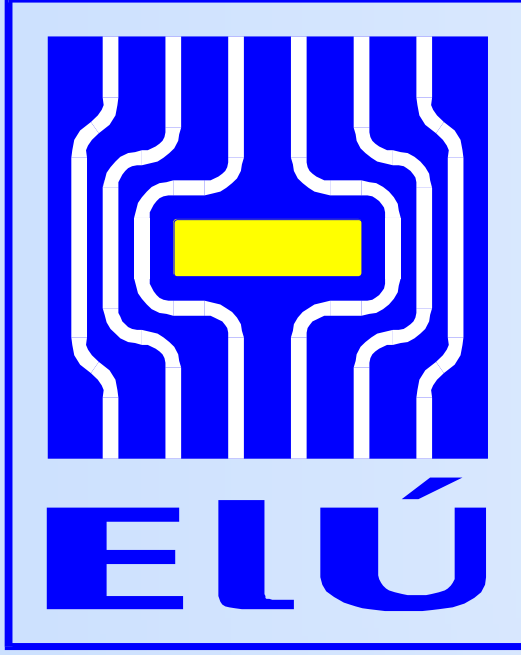


# From single silicon carbide detector to pixelated structure for radiation imaging camera

International Workshop  
23rd World  
on Radiation Imaging Detectors



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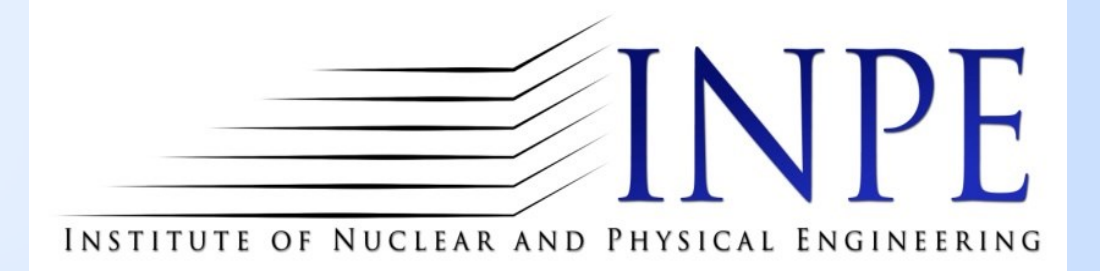
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## INTRODUCTION

Detectors based on 4H-SiC (Silicon Carbide) are very perspective due to:

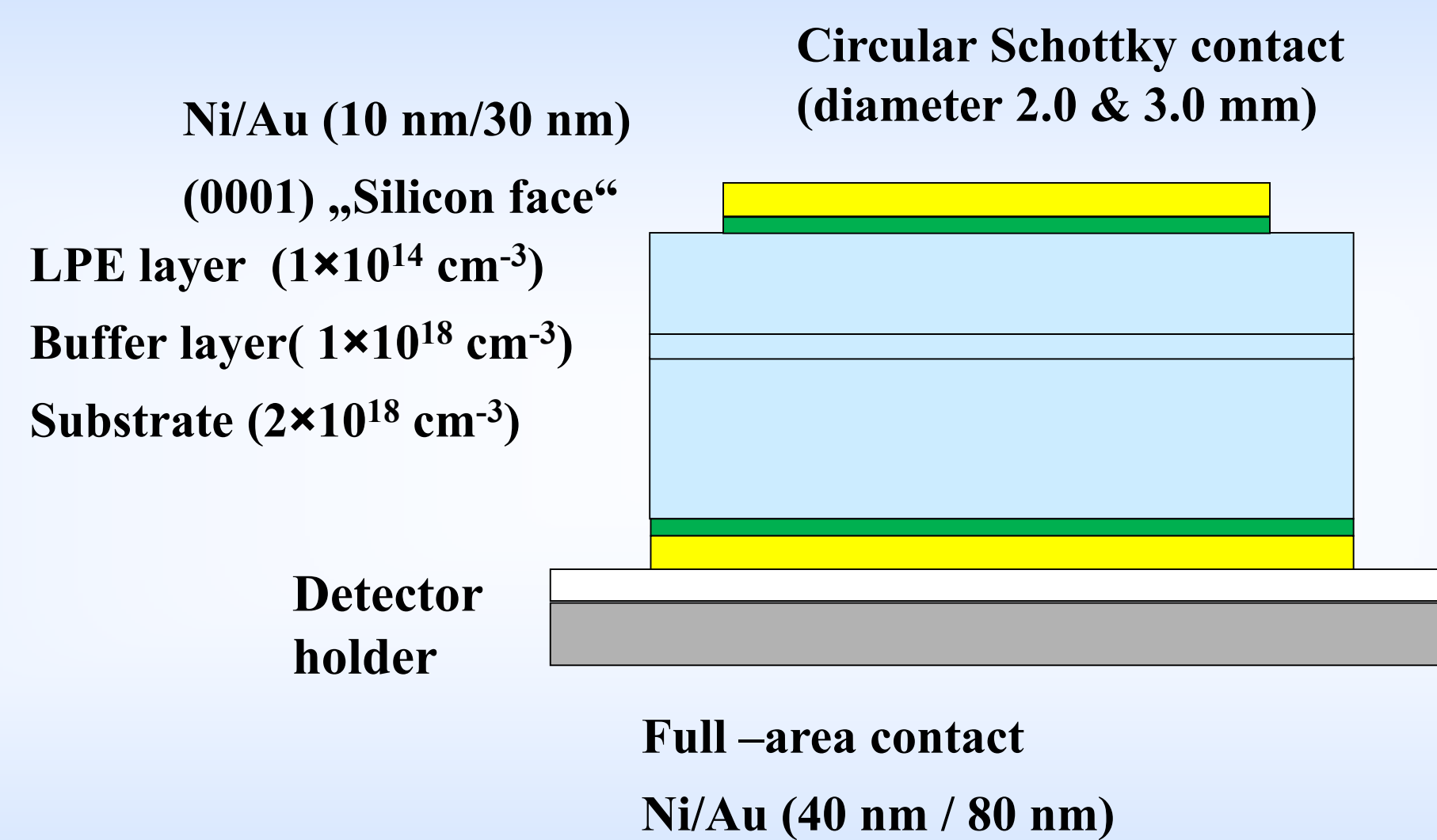
- high breakdown voltage ( $4 \times 10^6$  V/cm)
- electron mobility of about  $900 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$
- high electron saturation drift velocity ( $2 \times 10^7 \text{ cm s}^{-1}$ )
- band gap energy of 3.26 eV
- operation at increased temperature up to 500 °C
- good radiation hardness

## DETECTOR MATERIAL

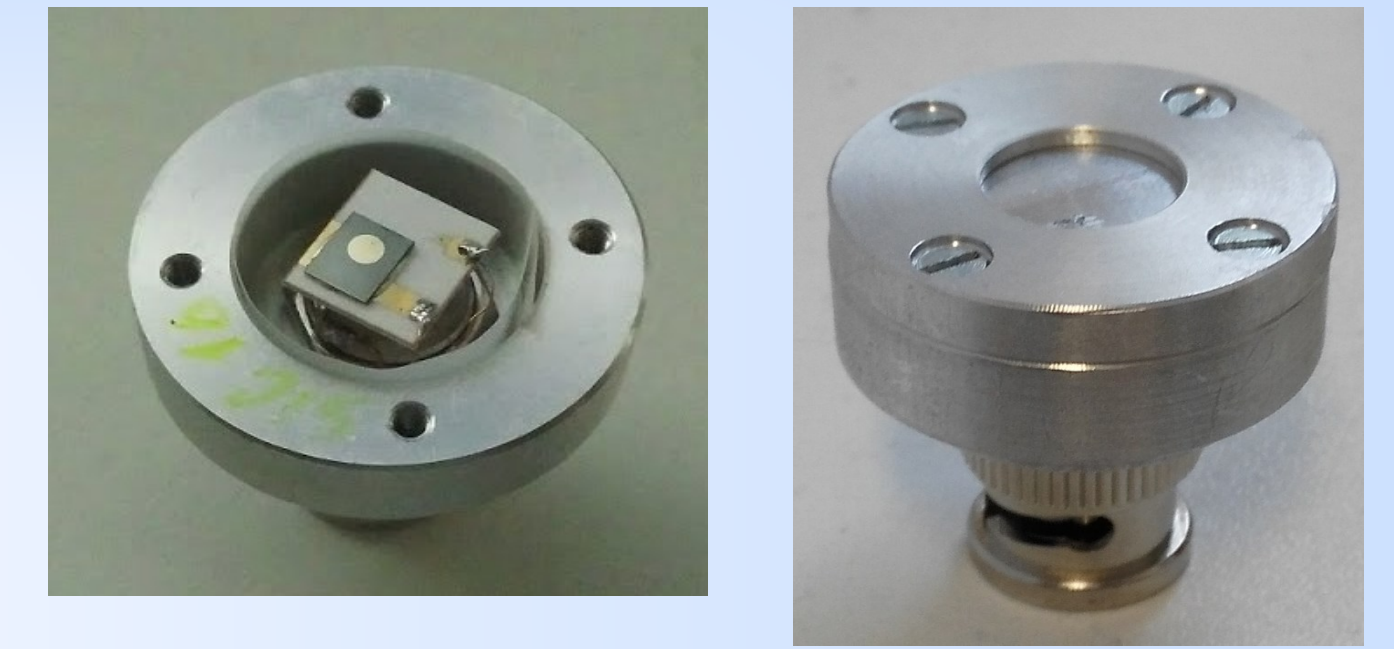
Base material parameters:

- 25, 50, 70  $\mu\text{m}$  thick nitrogen-doped 4H-SiC layer grown by LPE
- Doping concentration about  $1 \times 10^{14} \text{ cm}^{-3}$
- 4H-SiC  $n^{++}$  substrate (350  $\mu\text{m}$  thick)
- 0.5  $\mu\text{m}$  buffer layer  $n^+$ -SiC with concentration  $1 \times 10^{18} \text{ cm}^{-3}$

## CROSS-SECTION OF DETECTOR



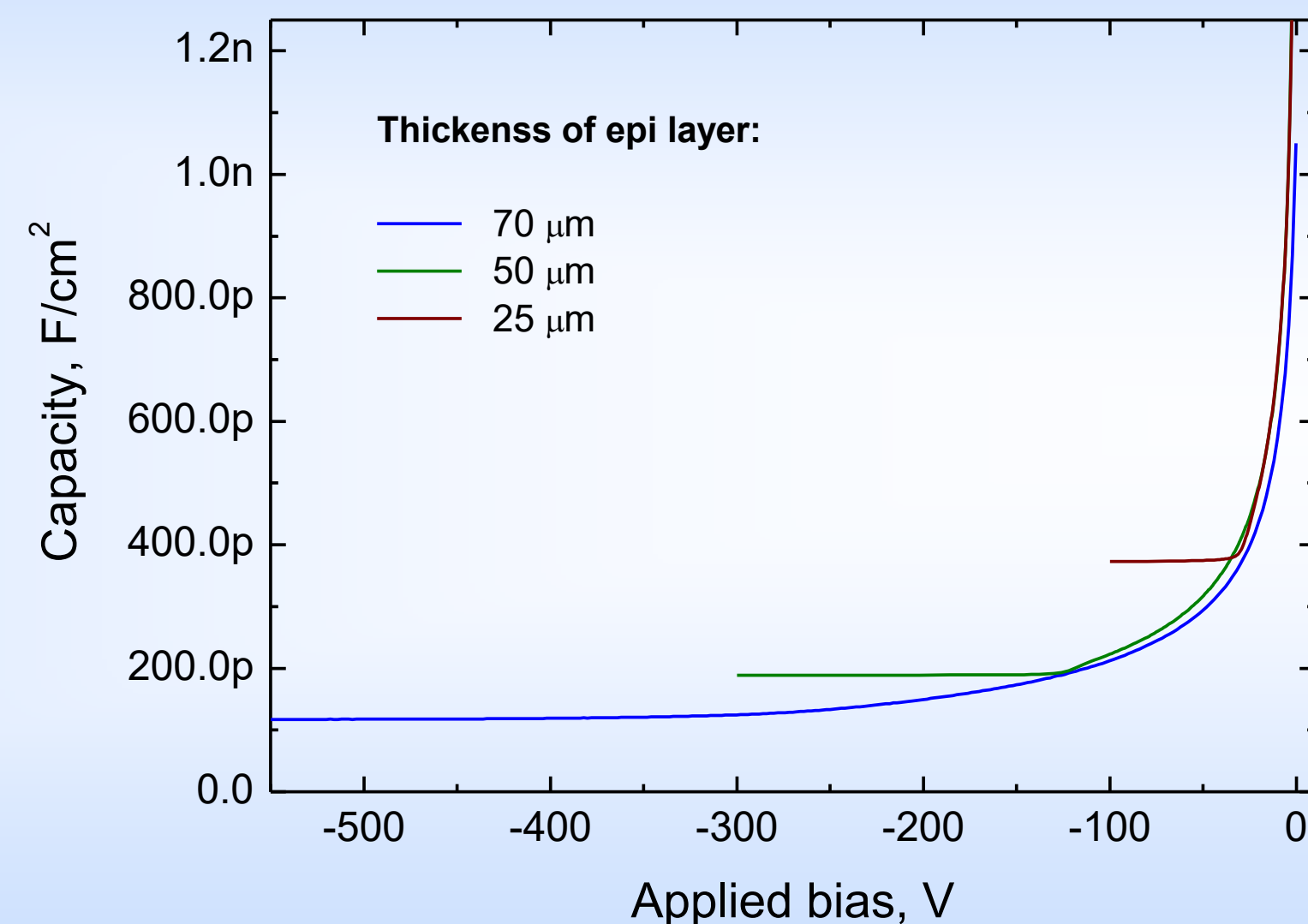
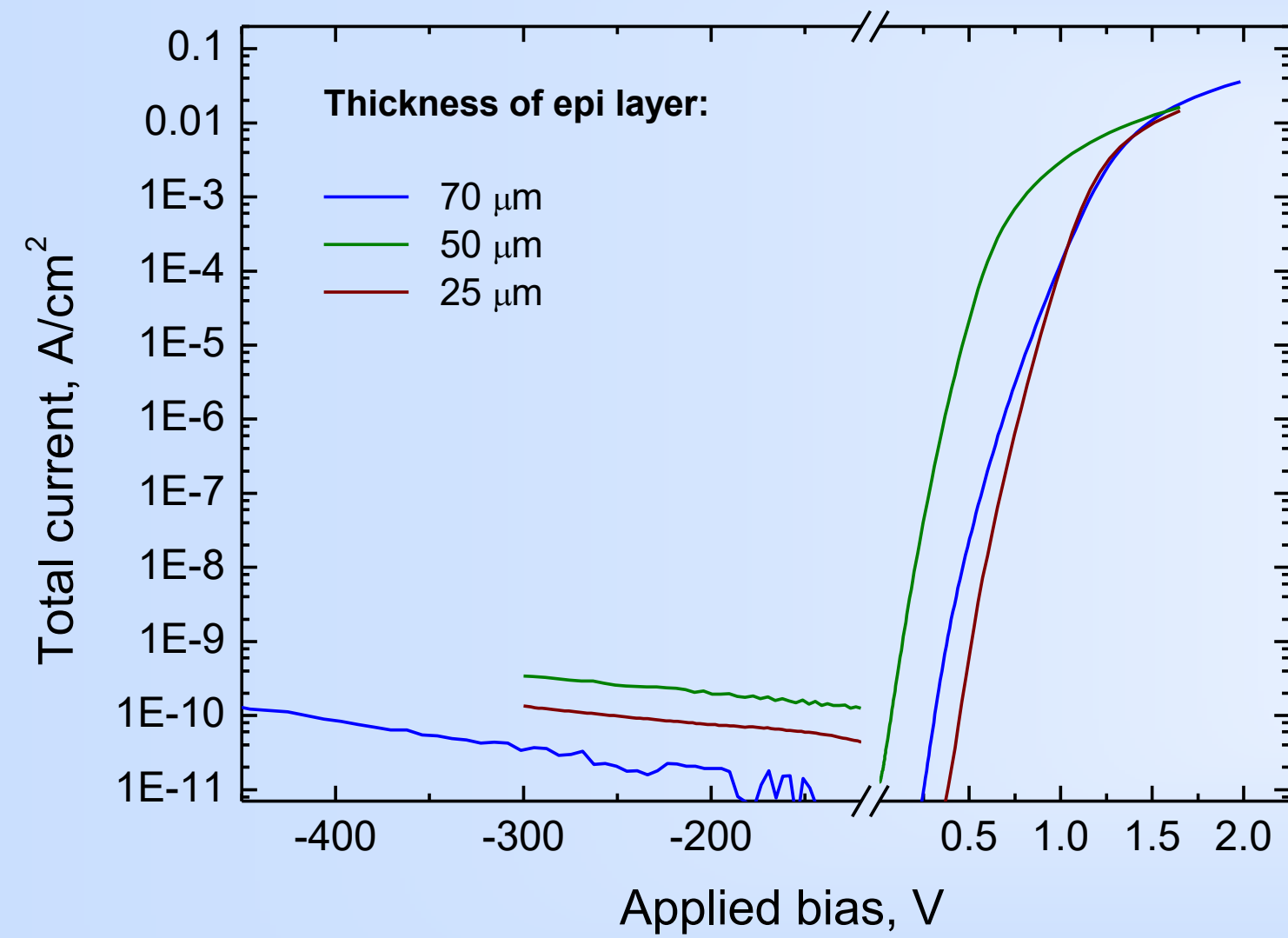
## PHOTOGRAPH OF DETECTOR



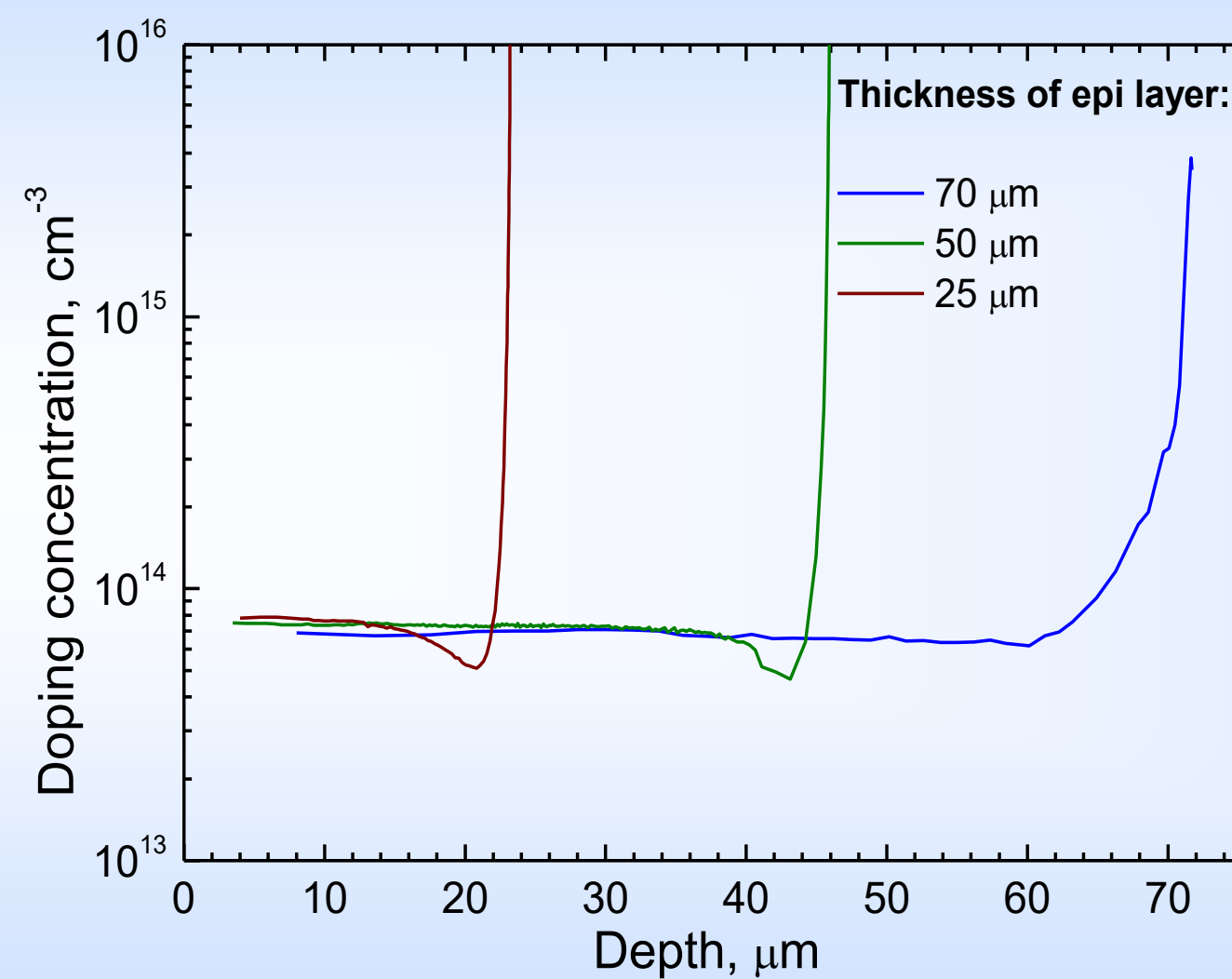
## EXPERIMENTAL METHODS

- Current-voltage measurements up to 1 kV;
- Capacitance-voltage measurements up to 600 V;
- Measuring system: Keithley system consisted of 4200A-SCS Parameter Analyzer completed by 4200A-CVIV Multi-Switch

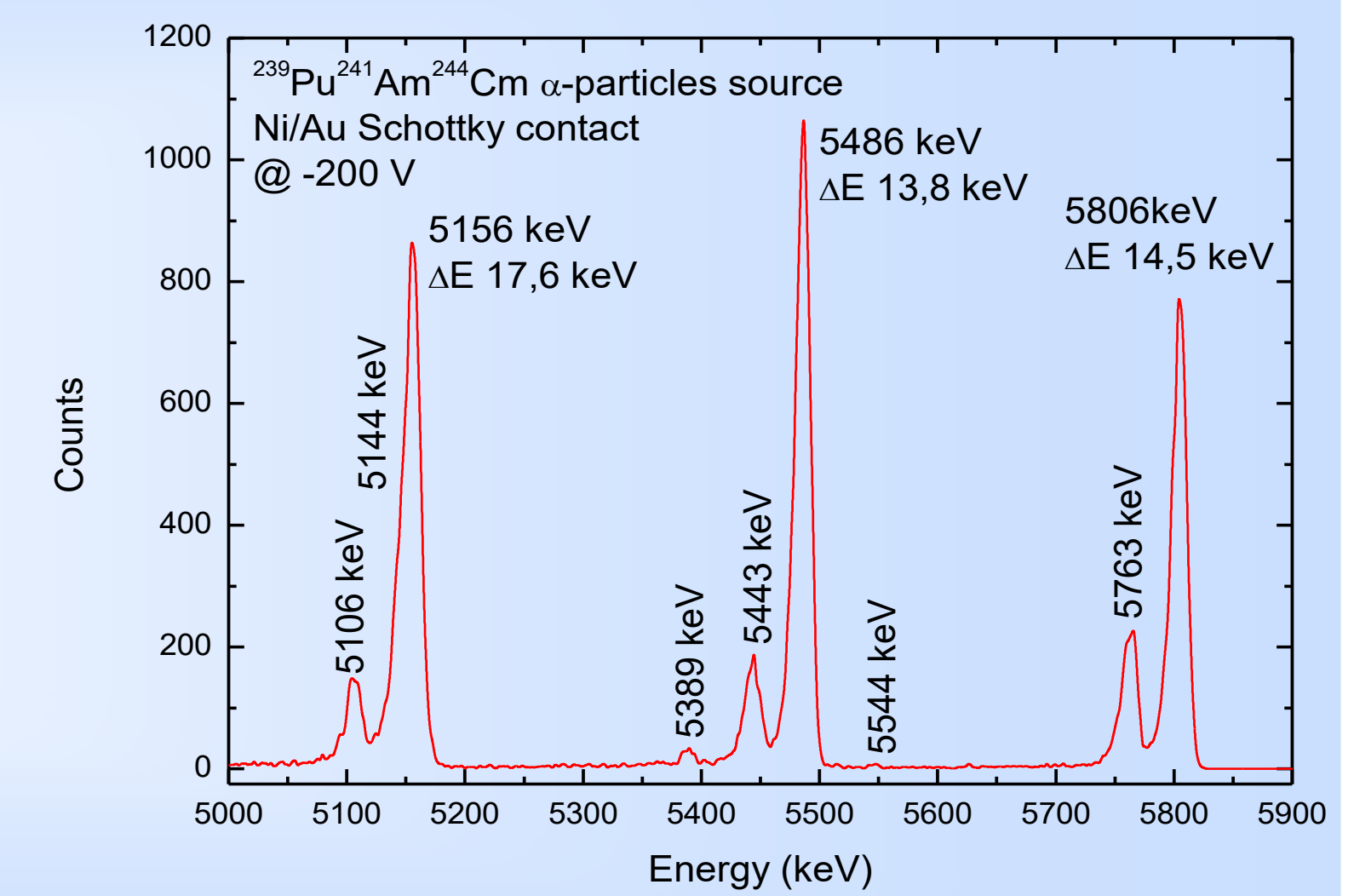
## CURRENT-VOLTAGE & CAPACITANCE-VOLTAGE MEASUREMENTS



## DEPLETION THICKNESS



## ALPHA PARTICLE SPECTRUM



## PIXEL STRUCTURES

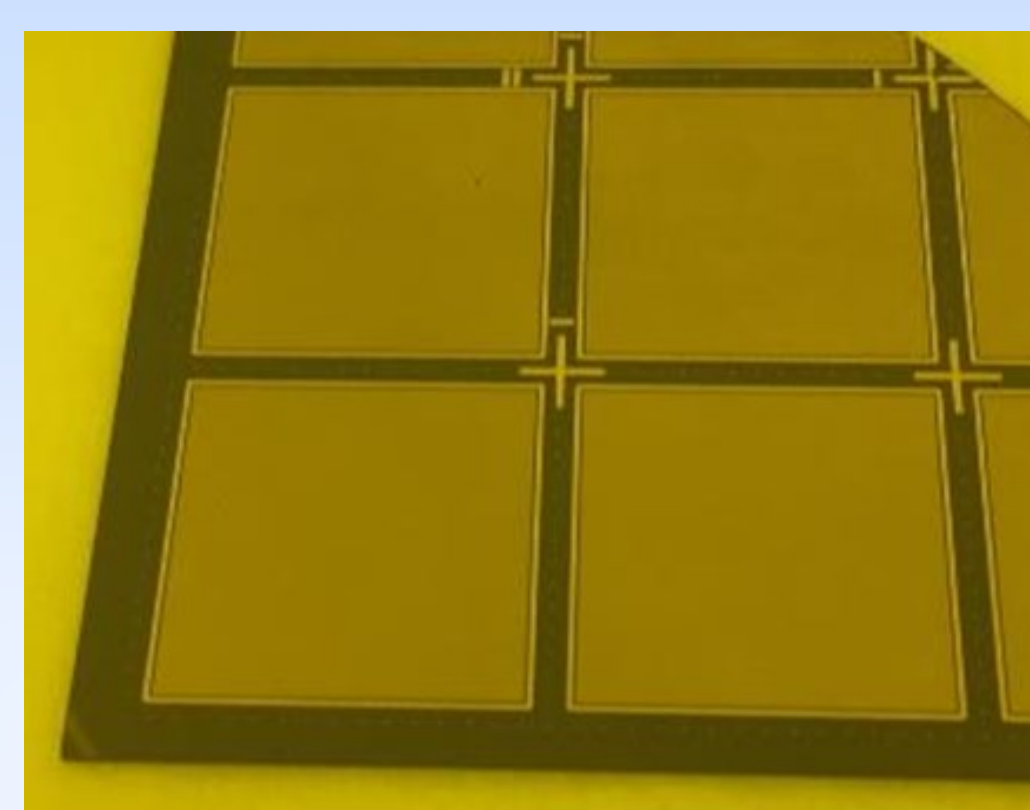
Base material parameters:

- 80  $\mu\text{m}$  and 100  $\mu\text{m}$  thick nitrogen-doped 4H-SiC layer grown by LPE
- Doping concentrations about  $7 \times 10^{13} \text{ cm}^{-3}$  and  $3 \times 10^{14} \text{ cm}^{-3}$
- 4H-SiC  $n^{++}$  substrate (350  $\mu\text{m}$  thick)
- 0.5  $\mu\text{m}$  buffer layer  $n^+$ -SiC with concentration  $1 \times 10^{18} \text{ cm}^{-3}$

Contacts preparation:

- Ni/Au (70/100 nm) Schottky contact
- Ti/Pt/Au (10/30/50 nm) Ohmic contact

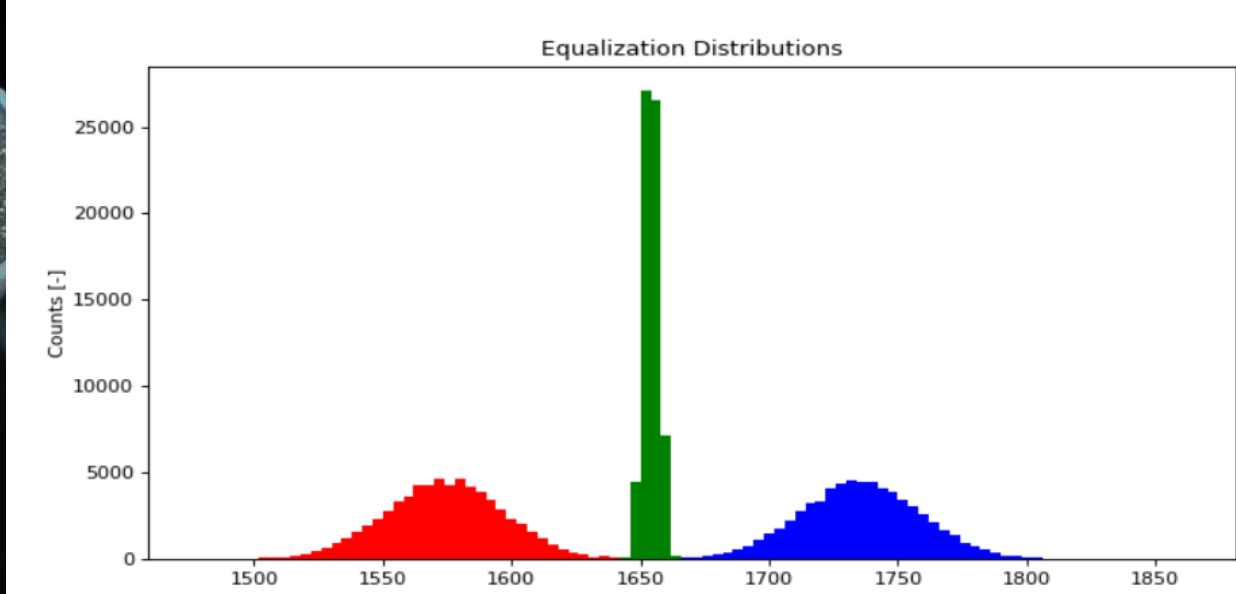
## PREPARED PIXELATED STRUCTURES



## TIMEPIX3 DETECTOR BASED ON 4H-SiC

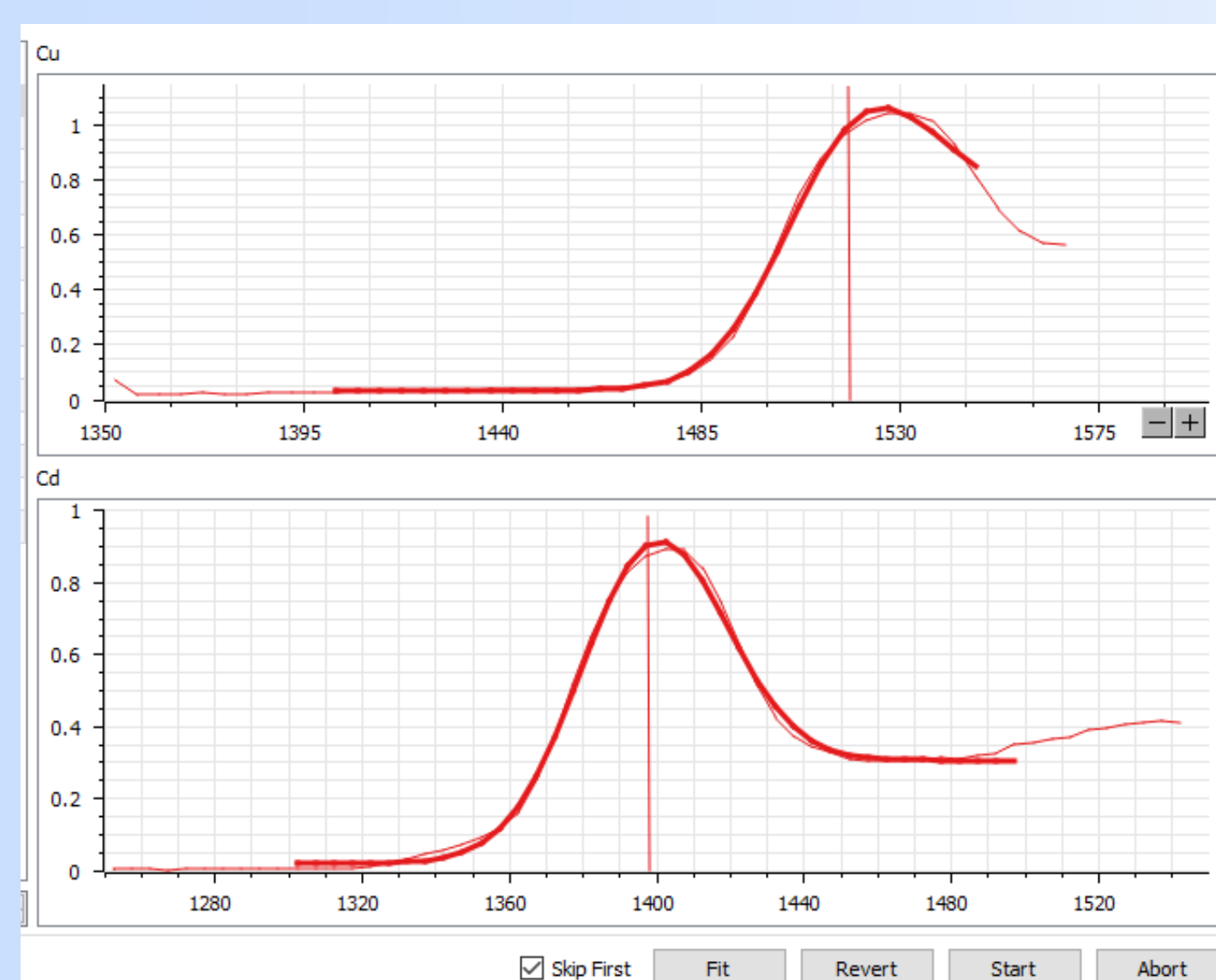


## Threshold Equalization

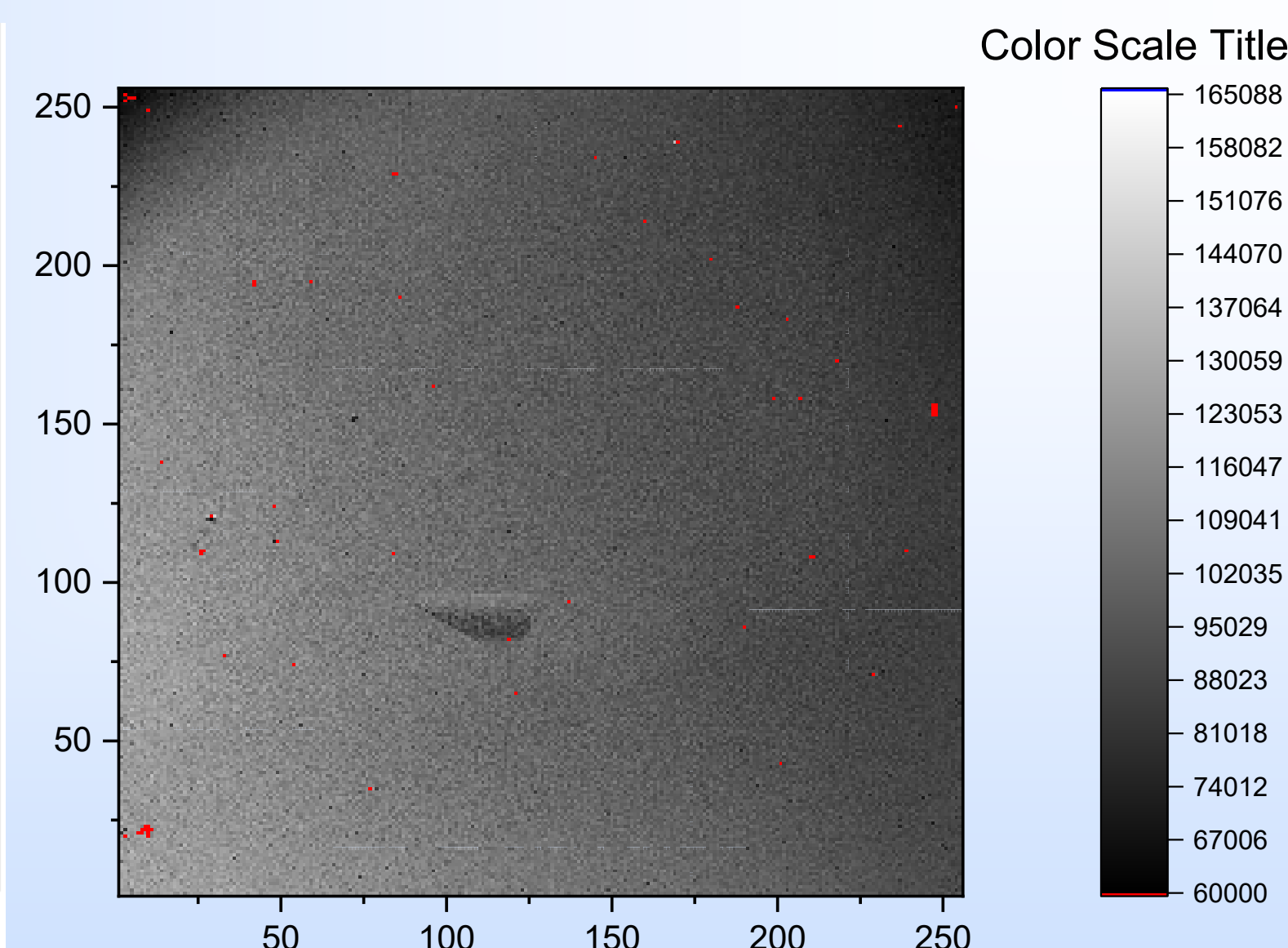


Parameter	Value
Mean THL	1654.224
Std. Dev	7.813
Masked Pixels	73
Final THL	0

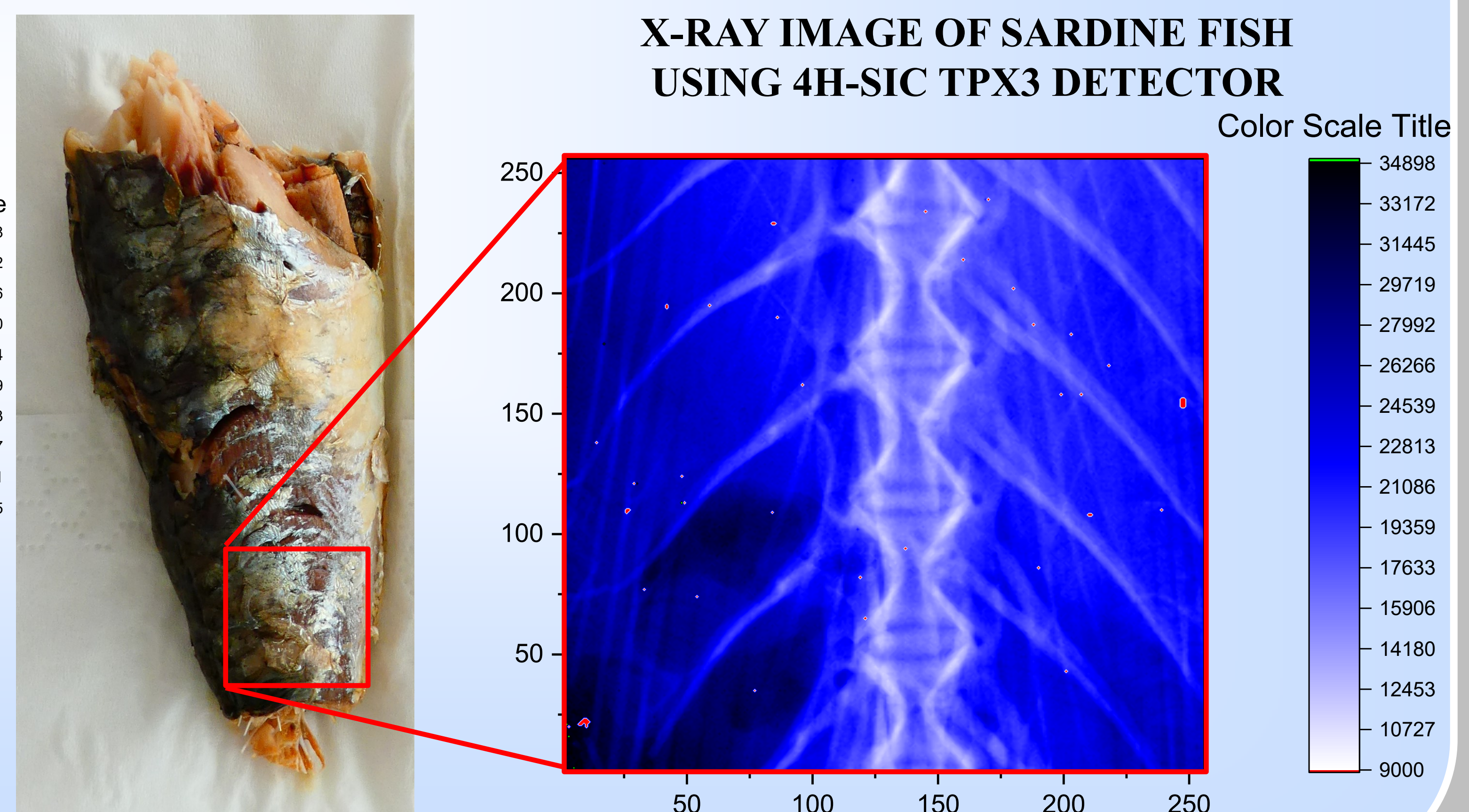
## THRESHOLD SCAN OF X-RAY PEAKS OF Cd AND Cu MATERIALS



## X-RAY BACKGROUND IMAGE OF 4H-SiC TPX3 DETECTOR



## X-RAY IMAGE OF SARDINE FISH USING 4H-SiC TPX3 DETECTOR



## SUMMARY

- We fabricated semiconductor detectors based on 4H-SiC epitaxial layer.
- Active layer consists of 4H-SiC LPE with thickness up to 100  $\mu\text{m}$ .
- The lowest doping concentration is below  $7 \times 10^{13} \text{ cm}^{-3}$ .
- The detector size was defined by circular Schottky contact with the diameter up to 3.0 mm.
- Detectors can obtain high energy resolution comparable to silicon detectors.
- We fabricated pixelated structures based on high-quality 4H-SiC epitaxial layer.
- Structures were bump-bonded to Timepix3 readout chips.
- We performed threshold equalization of new SiC Timepix3 detectors
- The threshold scan of Cd and Cu X-ray peaks shows good energy resolution of SiC Timepix3 detector.
- X-ray image of Sardine fish shows homogeneity of pixels and excellent quality of X-ray image.